

JAN 17 2006 520.43302PX1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Akira HAMAMASTU, et al.
Serial No.: 10/724,750
Filed: December 2, 2003
Title: METHOD FOR INSPECTING DEFECT AND APPARATUS FOR
INSPECTING DEFECT
Group: 2877
Examiner: STAFIRA, Michael Patrick
Confirmation No.: 2088

AMENDMENT

Mail Stop: Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

January 17, 2006

Sir:

In response to the Office Action dated September 16, 2005, the period of response for which extension of time is requested in the attached Petition for Extension of Time, please amend the above-identified application as listed below and as set forth on the following pages:

Amendments to the claims begin on page 2;

Remarks are included beginning on page 6; and

Authorization is included on page 11.